W

	Application No.	Applicant(s)
Notice of Allowability	10/656,267	HIRAKATA ET AL.
	Examiner	Art Unit
	Steven H. VerSteeg	1753
The MAILING DATE of this communication apperature All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this ap or other appropriate communication IGHTS. This application is subject to	plication. If not included
1. \boxtimes This communication is responsive to <u>foreign priority paper</u>	filing dated 1/20/04.	
2. The allowed claim(s) is/are <u>1-16</u> .		
3. \boxtimes The drawings filed on <u>08 September 2003</u> are accepted by	the Examiner.	
 4. Acknowledgment is made of a claim for foreign priority una) All b) Some* c) None of the: Certified copies of the priority documents have Certified copies of the priority documents have Copies of the certified copies of the priority documents have Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: 	been received. been received in Application No	
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file a reply IENT of this application.	complying with the requirements
5. A SUBSTITUTE OATH OR DECLARATION must be subminformal PATENT APPLICATION (PTO-152) which give	itted. Note the attached EXAMINER es reason(s) why the oath or declara	'S AMENDMENT or NOTICE OF tion is deficient.
6. CORRECTED DRAWINGS (as "replacement sheets") mus (a) including changes required by the Notice of Draftspers 1) hereto or 2) to Paper No./Mail Date (b) including changes required by the attached Examiner's Paper No./Mail Date ldentifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the	on's Patent Drawing Review (PTO- s Amendment / Comment or in the C .84(c)) should be written on the drawir he header according to 37 CFR 1.121(c	Office action of ngs in the front (not the back) of d).
 DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT I 	sit of BIOLOGICAL MATERIAL n FOR THE DEPOSIT OF BIOLOGICA	nust be submitted. Note the AL MATERIAL.
 Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 9/8/03 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material 	6. ☐ Interview Summary Paper No./Mail Dat 8), 7. ☑ Examiner's Amendn	
√		



Application/Control Number: 10/656,267 Page 2

Art Unit: 1753

EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Mark Woodall (Reg # 43,286) on April 25, 2005.

The application has been amended as follows:

In the claims:

Claim 6, line 3, please delete "gas type" and insert -kind of gas-

Claim 8, line 7, please delete "discharging" and insert –discharge—

Claim 9, line 9, please delete "discharging" and insert –discharge—

Reasons for Allowance

- 2. The following is an examiner's statement of reasons for allowance: it is neither anticipated nor obvious over the prior art of record to have a manufacturing apparatus for a carbon nanotube as claimed by Applicant in claim 1.
- 3. High-purity carbon nanotubes synthesis method by an arc discharging in magnetic field by Anazawa et al. (Anazawa) and US 2002/0179428 A1 to Anazawa et al. (Anazawa II) each disclose a manufacturing apparatus for a carbon nanotube comprising at least two electrodes, at least a power supply, and at least a plurality of magnets that generate a magnetic field in multiple directions or parallel with a flowing direction of a discharge current, but there is no thermal shield wall made of non-magnetic material between the magnets and the generation area of the

discharge plasma. The magnets appear to be directly within the chamber adjacent to the electrodes. There is no motivation to place a thermal shield wall in the apparatus of Anazawa or Anazawa II unless hindsight reasoning is used.

- 4. US 2003/0173206 A1 to Delaunay et al. (Delaunay) discloses a system comprising electromagnets, but the magnetic field is different than that claimed by Applicant. Also, there are no electrodes opposed with tips as currently claimed.
- 5. US 6,063,243 to Zettl et al. (Zettl) discloses an apparatus for producing nanotubes, but there is no plurality of magnets.
- 6. Combining Delaunay with either Zettl, Anazawa or Anazawa II is only possible if Applicant's claimed invention is used as a guide.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

General Information

For general status inquiries on applications not having received a first action on the merits, please contact the Technology Center 1700 receptionist at (571) 272-1700.

For inquiries involving Recovery of lost papers & cases, sending out missing papers, resetting shortened statutory periods, or for restarting the shortened statutory period for response, please contact Denis Boyd at (571) 272-0992.

For general inquiries such as fees, hours of operation, and employee location, please contact the Technology Center 1700 receptionist at (571) 272-1300.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Steven H. VerSteeg whose telephone number is (571) 272-1348. The examiner can normally be reached on Mon - Thurs (6:30 AM - 5:00 PM).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nam X. Nguyen can be reached on (571) 272-1342. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Steven H VerSteeg Primary Examiner

Art Unit 1753

shv

April 21, 2005